



Driving Down HB-LED Costs (Part 2): Advanced Chemistry Models for MOCVD Reactor Design/Optimization

Project title:

Driving Down HB-LED Costs: Implementation of Process Simulation Tools and Temperature Control for High Yield MOCVD Growth

Team Members:

Veeco Instruments, Sandia National Laboratories, Philips Lumileds

Overall Goal:

Reduce LED cost by 4x through increased MOCVD growth yield, improved efficiency, and better productivity

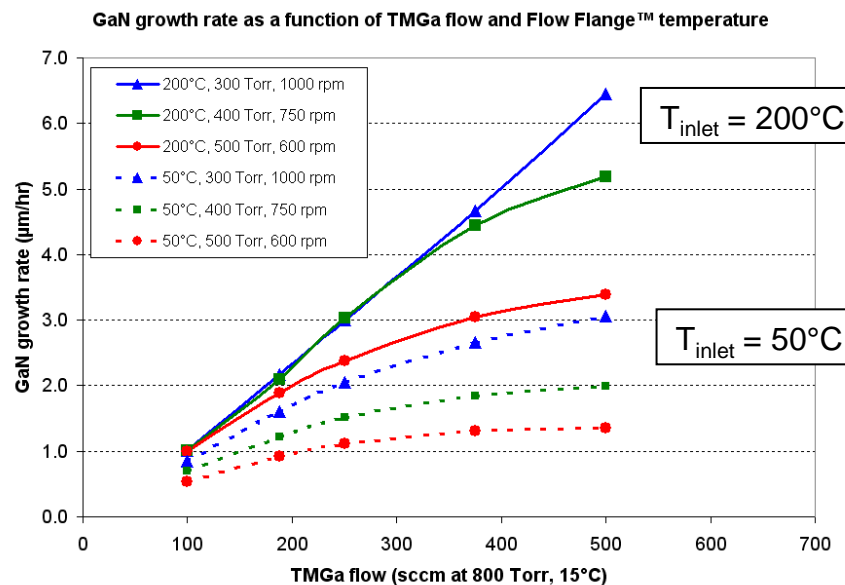
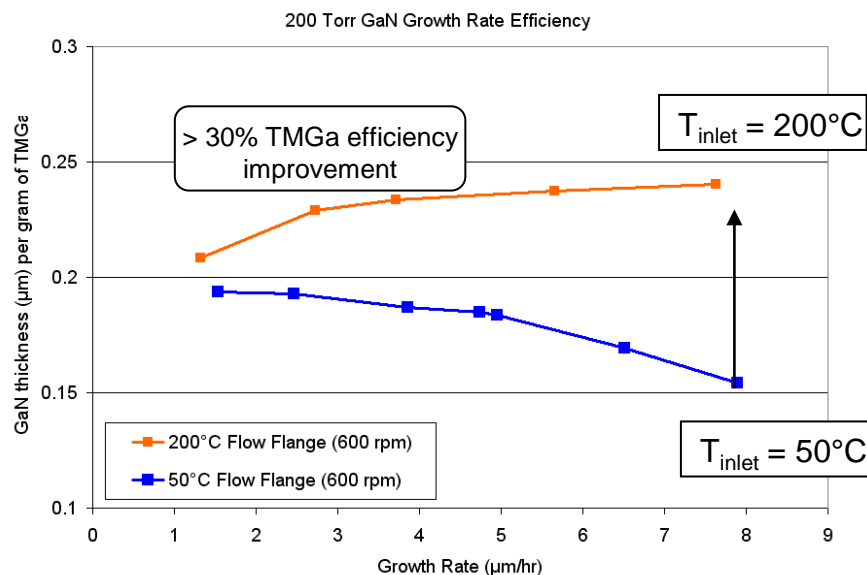
Manufacturing R&D MYPP targets:

**A4.4 Manufacturing simulation; B4.1 Yield manufacturability;
B4.2 Epitaxial growth; B4.3 Manufacturing tools**

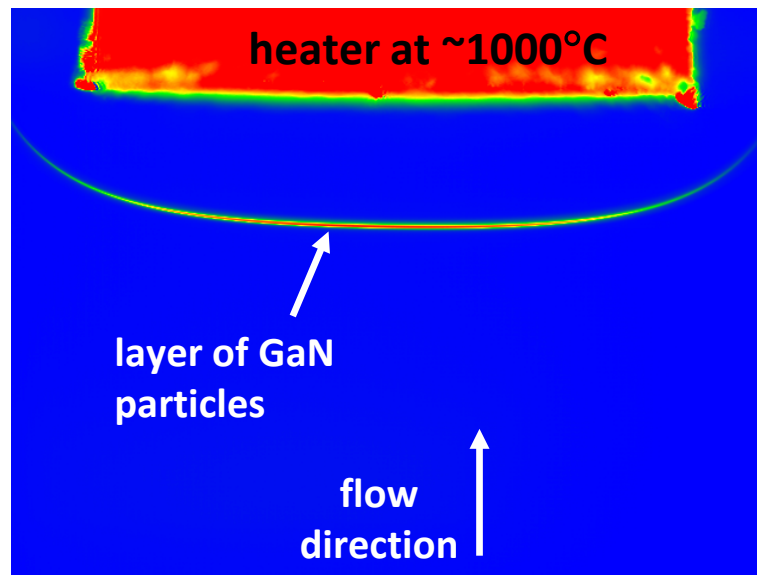
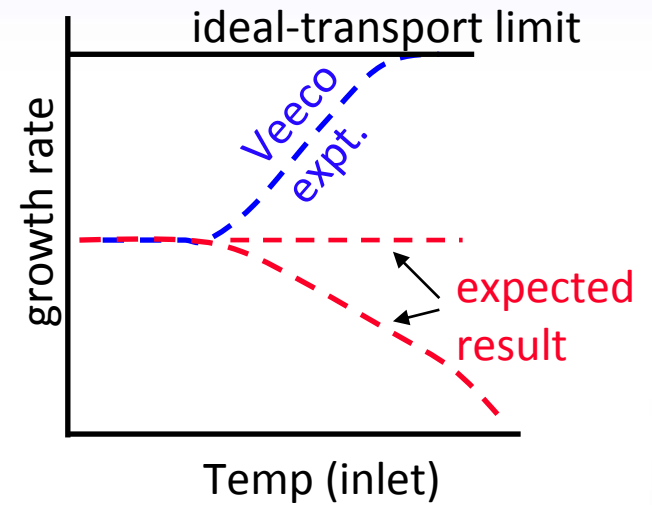
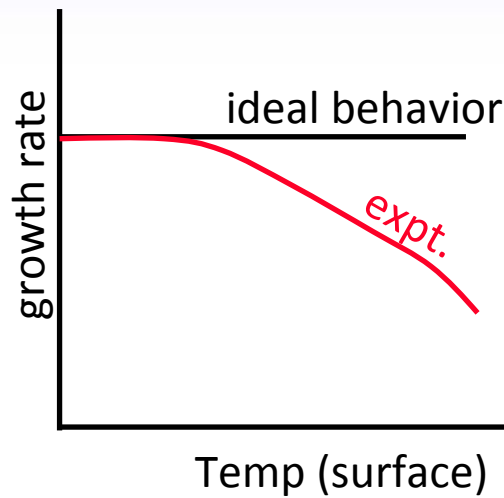
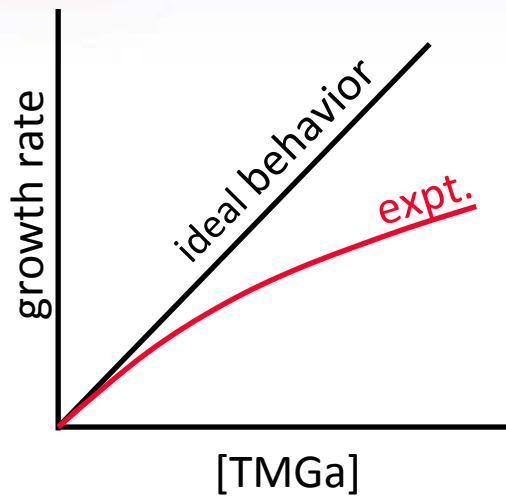
Heated Flow Flange

GaN Growth Source Efficiency

At a gas inlet temperature of 200°C, metal organic efficiency increases by more than 30% at high growth rates of GaN



Growth Rates Dominated by Gas-Phase Particle Chemistry



Particle Formation Explains MOCVD Growth Rate Behavior

